

HEREBY CERTIFY THAT THIS CORRESPONDENCE IS BEING DEPOSITED WITH THE UNITED STATES POSTAL SERVICE AS FIRST CLASS MAIL IN AN ENVELOPE
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7/28/03
(Date of Deposit)
Karen Cinq-Mars 7/28/03
Karen Cinq-Mars (Signature & Date)

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

<u>In Re Application of</u> :	July 28, 2003
<u>Shahid Butt et al.</u> :	Art Unit:
<u>Serial No. 10/604,519</u> :	Examiner: Unknown
<u>Filed: July 28, 2003</u> :	IBM Corporation Dept. 18G/Bldg. 300-482 2070 Route 52, Hopewell Junction, New York 12533-6531
<u>Title: METHOD AND APPARATUS FOR AMPLITUDE FILTERING IN THE FREQUENCY PLANE OF A LITHOGRAPHIC PROJECTION SYSTEM</u> :	

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

Commissioner for Patents
P. O. Box 1450
Arlington, Va 22313-1450

Sir:

Pursuant to the duty of disclosure set forth in 37 CFR 1.56, and further pursuant to 37 CFR 1.97 and 37 CFR 1.98, Applicants hereby respectfully submit copies of the following documents as listed on Form PTO-1449, attached hereto.

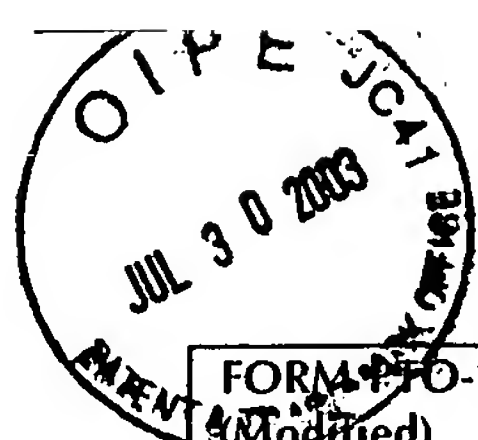
Please charge any fees in connection with this statement to Deposit Account # 09-0458.

Respectfully submitted,

By Todd M. C. Li
Todd M. C. Li, Attorney
Registration No. 45,554
Telephone No. (845)894-6919

TML/kcm

FIS920030150

Sheet 1 of 1

FORM PTO-1449 (Modified)	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO.: FIS920030150US1	SERIAL NO.: 10/604,519
SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT BY APPLICANT		APPLICANT: Shahid Butt et al.	
(Use several sheets if necessary) (37 CFR 1.98(b))		FILING DATE: July 28, 2003	GROUP:

REFERENCE DESIGNATION

U.S. PATENT DOCUMENTS

EXAMINER INITIAL		PATENT NUMBER	ISSUE DATE	PATENTEE	CLASS	SUB- CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
	AF						
	AG						
	AH						
	AI						
	AJ						
	AK						

FOREIGN PATENT DOCUMENTS

			PUBLICATION DATE	COUNTRY OR PATENT OFFICE		SUB- CLASS	TRANSLATION	
		DOCUMENT NUMBER			CLASS		YES	NO
	AL							
	AM							
	AN							
	AO							
	AP							

OTHER ART (Including Author, Title, Date, Pertinent Pages, etc.)

	AQ	"Characterization of Super-Resolution Photolithography", H. Fukuda, R. Yamanaka, T. Terasawa, K. Hama, T. Tawa and S. Okazaki, IEEE, 4/1992, pages 3.2.1-3.2.4.
	AR	"Resolution Enhancement by Oblique Illumination Optical Lithography Using a Pupil Filter", T. Horiuchi, Y. Takeuchi, S. Matsuo and K. Harada, IEEE, 1993, pages 27.3.1-27.3.4
	AS	

EXAMINER

DATE CONSIDERED

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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